The documentation and process conversion measures necessary to comply with this revision shall be completed by 7 February 2020.

INCH-POUND
MIL-PRF-19500/775B
7 November 2019
SUPERSEDING
MIL-PRF-19500/775A
3 December 2018

PERFORMANCE SPECIFICATION SHEET

TRANSISTOR, FIELD EFFECT RADIATION HARDENED, N-CHANNEL, SILICON, TYPES 2N7647 AND 2N7648, QUALITY LEVELS JANTXV AND JANS

This specification is approved for use by all Departments and Agencies of the Department of Defense.

The requirements for acquiring the product described herein shall consist of this specification sheet and MIL-PRF-19500.

1. SCOPE

- 1.1 <u>Scope</u>. This specification covers the performance requirements for an N-channel, enhancement-mode, MOSFET, radiation hardened (total dose and single event effects (SEE)), power transistor. Two levels of product assurance (JANTXV and JANS) are provided for each encapsulated device. Provisions for radiation hardness assurance (RHA) to two radiation levels ("R" and "F") are provided for JANTXV and JANS product assurance level.
- 1.2 <u>Package outlines</u>. The device package outlines are as follows: TO-257AA (T3) in accordance with figure 1, a modified tab-lessTO-257AA (D5) in accordance with figure 2, and a surface mount TO-276AA (U3, U3C) in accordance with figure 3 for all encapsulated device types.
 - 1.3 Maximum ratings. T_A = +25°C, unless otherwise specified.

Туре	P _T (1) T _C = +25°C	P _T T _A = +25°C	R _θ JC (2)	V _{DS}	V _{DG}	V _G S	I _{D1} (3) (4) T _C = +25°C	I _{D2} T _C = +100°C	ls	I _{DM} (5)	T _J and T _{STG}	V _{ISO} 70,000 ft. altitude
	<u>W</u>	<u>W</u>	°C/W	V dc	V dc	V dc	A dc	A dc	A dc	<u>A (pk)</u>	<u> </u>	<u>V dc</u>
2N7647U3, 2N7647U3C	75	1.56	1.67	60	60	±20	40	29	40	160		
2N7647T3, 2N7647D5	75	1.56	1.67	60	60	±20	30	28	30	120	-55 to	250
2N7648U3, 2N7648U3C	75	1.56	1.67	100	100	±20	35	22	35	140	+150	230
2N7648T3, 2N7648D5	75	1.56	1.67	100	100	±20	30	22	30	120		

- (1) Derate linearly by 0.6 W/°C for T_C > +25°C.
- (2) See figure 4, thermal impedance curves.
- (3) The following formula derives the maximum theoretical I_D limit. I_D is limited by package and internal wires and may be limited by pin diameter: $I_D = \sqrt{\frac{T_{JM} T_C}{\left(R_{\theta JC}\right) x \left(R_{DS} \left(\text{on}\right) \text{ at } T_{JM}\right)}}$
- (4) See figure 5, maximum drain current graph.
- (5) $I_{DM} = 4 \times I_{D1}$; I_{D1} as calculated by footnote (3).

Comments, suggestions, or questions on this document should be addressed to DLA Land and Maritime, ATTN: VAC, P.O. Box 3990, Columbus, OH 43218-3990, or emailed to Semiconductor@dla.mil. Since contact information can change, you may want to verify the currency of this address information using the ASSIST Online database at https://assist.dla.mil/.

AMSC N/A

* 1.4 Primary electrical characteristics at T_C = +25°C.

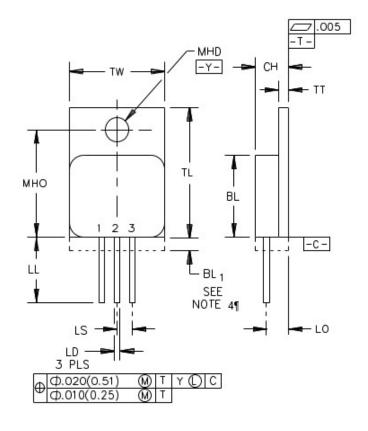
Туре	$\begin{aligned} & \text{Min V}_{(BR)DSS} \\ & \text{V}_{GS} = 0 \\ & \text{I}_{D} = 1.0 \text{mA dc} \end{aligned}$	$V_{GS} = 0$ $V_{DS} \ge V_{GS}$ V_{CS}		Max r _{Ds} V _{GS} = 12'	Eas	
			of rated V _D	T _J = +25°C	T _J = +150°C	
	V dc	<u>V dc</u> <u>Min Max</u>	μA dc	Ω	Ω	<u>mJ</u>
2N7647U3, 2N7647U3C	60	2.0 4.0	1.0	0.018	0.038	840
2N7647T3, 2N7647D4	60	2.0 4.0	1.0	0.019	0.040	784
2N7648U3, 2N7648U3C	100	2.0 4.0	1.0	0.034	0.062	605
2N7648T3, 2N7648D4	100	2.0 4.0	1.0	0.035	0.064	605

- (1) Pulsed (see 4.5.1).
- 1.5 <u>Part or Identifying Number (PIN)</u>. The PIN is in accordance with MIL-PRF-19500, and as specified herein. See 6.5 for PIN construction example and 6.6 for a list of available PINs.
- 1.5.1 <u>JAN certification mark and quality level</u>. The only quality level designators for encapsulated devices that are applicable for this specification sheet are the quality levels "JANTXV" and "JANS".
- 1.5.2 <u>Radiation hardness assurance (RHA) designator</u>. The RHA levels that are applicable for this specification sheet from lowest to highest are as follows: "R" and "F".
- 1.5.3 <u>Device type</u>. The designation system for the device types of transistors covered by this specification sheet are as follows.
- 1.5.3.1 <u>First number and first letter symbols</u>. The transistors of this specification sheet use the first number and letter symbols "2N".
- * 1.5.3.2 <u>Second number symbols</u>. The second number symbols for the transistors covered by this specification sheet are as follows: "7647" and "7648".
 - 1.5.4 Suffix letters. The following suffix letters are incorporated in the PIN for this specification sheet:

Т3	Indicates a metal lidded 3 terminal leaded package similar to a TO-257AA (see figure 1)
D5	Indicates a metal lidded 3 terminal leaded package similar to a tab-less TO-257AA (see figure 2)
U3	Indicates a metal lidded 3 pad surface mount package similar to a TO-276AA (SMD-0.5) (see figure 3).
U3C	Indicates a ceramic lidded 3 pad surface mount package similar to a TO-276AA (SMD-0.5) (see figure 3).

1.5.5 Lead finish. The lead finishes applicable to this specification sheet are listed on QPDSIS-19500.

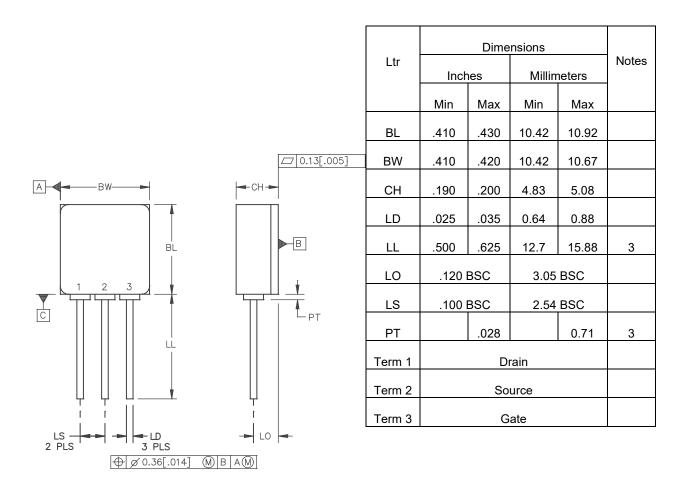
	Dimensions					
Ltr	Inch	nes	Millir	neters		
	Min	Max	Min	Max		
BL	.410	.430	10.41	10.92		
BL ₁		.033		0.84		
СН	.190	.200	4.83	5.08		
LD	.025	.035	0.64	0.89		
LL	.600	.650	15.24	16.51		
LO	.120 BS	SC	3.05 BSC			
LS	.100 BS	SC .	2.54 BSC			
MHD	.140	.150	3.56	3.81		
МНО	.527	.537	13.39	13.64		
TL	.645	.665	16.38	16.89		
TT	.035	.045	0.89	1.14		
TW	.410	.420	10.41	10.67		
Term 1	Drain					
Term 2	Source					
Term 3	Gate					



NOTES:

- 1. Dimensions are in inches.
- 2. Millimeters are given for general information only.
- 3. All terminals are isolated from the case.
- 4. This area is for the lead feed-thru eyelets (configuration is optional, but will not extend beyond this zone).
- 5. In accordance with ASME Y14.5M, diameters are equivalent to φx symbology.

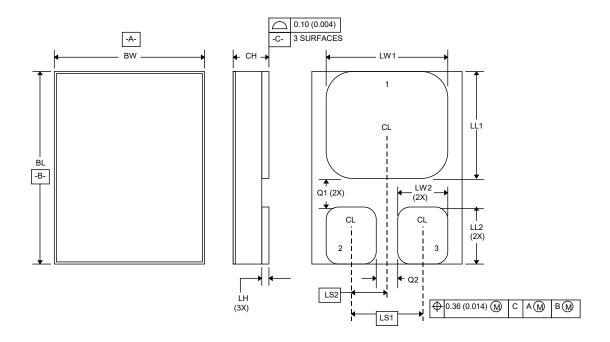
FIGURE 1. Dimensions and configuration, TO-257AA (T3).



NOTES:

- 1. Dimensions are in inches.
- 2. Millimeters are given for general information only.
- 3. Protrusion thickness (PT) of ceramic eyelets included in dimension LL.
- 4. All terminals are isolated from case.
- 5. In accordance with ASME Y14.5M, diameters are equivalent to φx symbology.

FIGURE 2. Physical dimensions for TO-257AA modified (tab-less package metal lid) D5.



Curahal	Dimensions					
Symbol	Inche	es	Millimeters			
	Min	Max	Min	Max		
BL	.395	.405	10.04	10.28		
BW	.291	.301	7.40	7.64		
CH (for U3)		.124		3.15		
CH (for U3C)		.134		3.39		
LH	.010	.020	0.25	0.51		
LW1	.281	.291	7.14	7.39		
LW2	.090	.100	2.29	2.54		
LL1	.220	.230	5.59	5.84		
LL2	.115	.125	2.93	3.17		
LS1	.150 B	SC	3.81 BSC			
LS2	.075 B	SC	1.91 BSC			
Q1	.030		0.762			
Q2	.030		0.762			
TERM 1		Dra	in	•		
TERM 2	Gate					
TERM 3		Soul	rce			

NOTES:

- 1. Dimension are in inches.
- 2. Millimeters are given for information only.
- 3. The lid shall be electrically isolated from the drain, gate, and source.
- 4. In accordance with ASME Y14.5M, diameters are equivalent to φx symbology.
- 5. Metal lid: U3 suffix; Ceramic lid: U3C suffix.

FIGURE 3. Dimensions and configuration (TO-276AA, SMD-0.5), with metal lid or ceramic lid.

2. APPLICABLE DOCUMENTS

2.1 <u>General</u>. The documents listed in this section are specified in sections 3 and 4 of this specification. This section does not include documents cited in other sections of this specification or recommended for additional information or as examples. While every effort has been made to ensure the completeness of this list, document users are cautioned that they must meet all specified requirements of documents cited in sections 3 and 4 of this specification, whether or not they are listed.

2.2 Government documents.

2.2.1 <u>Specifications, standards, and handbooks</u>. The following specifications, standards, and handbooks form a part of this document to the extent specified herein. Unless otherwise specified, the issues of these documents are those cited in the solicitation or contract.

DEPARTMENT OF DEFENSE SPECIFICATIONS

MIL-PRF-19500 - Semiconductor Devices, General Specification for.

DEPARTMENT OF DEFENSE STANDARDS

MIL-STD-750 - Test Methods for Semiconductor Devices.

MIL-STD-883 - Test Method Standard Microcircuits

(Copies of these documents are available online at https://quicksearch.dla.mil/).

2.3 <u>Order of precedence</u>. Unless otherwise noted herein or in the contract, in the event of a conflict between the text of this document and the references cited herein, the text of this document takes precedence. Nothing in this document, however, supersedes applicable laws and regulations unless a specific exemption has been obtained.

3. REQUIREMENTS

- 3.1 General. The individual item requirements shall be as specified in MIL-PRF-19500 and as modified herein.
- 3.2 <u>Qualification</u>. Devices furnished under this specification shall be products that are manufactured by a manufacturer authorized by the qualifying activity for listing on the applicable qualified manufacturer's list (QML) before contract award (see 4.2 and 6.3).
- 3.3 <u>Abbreviations, symbols, and definitions</u>. Abbreviations, symbols, and definitions used herein shall be as specified in MIL-PRF-19500.
- 3.4 <u>Interface and physical dimensions</u>. The interface and physical dimensions shall be as specified in <u>MIL-PRF-19500</u> and on figures 1 (T3, TO-257AA with metal lid), 2 (TO-257AA with metal lid and tab-less), and 3 (U3, U3C, surface mount TO-276AA) herein.
- 3.4.1 <u>Lead finish</u>. Lead finish shall be solderable in accordance with MIL-PRF-19500, MIL-STD-750, and herein. Where a choice of lead finish is desired, it shall be specified in the acquisition document (see 6.2).
- 3.4.2 <u>Multiple chip construction</u>. Multiple chip construction is not permitted to meet the requirements of this specification.
- 3.4.3 <u>Silicone die coat</u>. The use of a silicone die coat requires a successful completion of MIL-STD-883, method 5011 on each epoxy lot for its intended applications, and as part of the full MIL-PRF-19500 qualification process.
 - 3.5 Marking. Marking shall be in accordance with MIL-PRF-19500.

- 3.6 <u>Electrical performance characteristics</u>. Unless otherwise specified herein, the electrical performance characteristics are as specified in 1.3, 1.4, and table I.
- 3.7 <u>Electrostatic discharge sensitive (ESDS)</u>. The devices covered by this specification sheet have been classified as ESDS. The devices shall be handled in accordance with the ESD program established to comply with the requirements of MIL-PRF-19500 to avoid damage due to the accumulation of static charge. The following handling practices shall be followed:
 - a. Devices should be handled on benches with conductive handling devices.
 - b. Ground test equipment, tools, and personnel handling devices.
 - c. Do not handle devices by the leads.
 - d. Store devices in conductive foam or carriers.
 - e. Avoid use of plastic, rubber, or silk in MOS areas.
 - f. Maintain relative humidity above 50 percent if practical.
 - g. Care should be exercised during test and troubleshooting to apply not more than maximum rated voltage to any lead.
 - h. Gate shall be terminated to source, R \leq 100 k Ω , whenever bias voltage is to be applied drain to source.
- 3.8 <u>Workmanship</u>. Semiconductor devices shall be processed in such a manner as to be uniform in quality and shall be free from other defects that will affect life, serviceability, or appearance.
 - 4. VERIFICATION
 - 4.1 <u>Classification of inspections</u>. The inspection requirements specified herein are classified as follows:
 - a. Qualification inspection (see 4.2).
 - b. Screening (see 4.3).
 - c. Conformance inspection (see 4.4 and tables I and II).
- 4.2 Qualification inspection. Qualification inspection shall be in accordance with MIL-PRF-19500 and as specified herein.
- 4.2.1 <u>Group E qualification</u>. Group E inspection shall be performed for qualification or re-qualification only. In case qualification was awarded to a prior revision of the specification sheet that did not request the performance of table III tests, the tests specified in table III herein that were not performed in the prior revision shall be performed on the first inspection lot of this revision to maintain qualification.
- 4.2.1.1 <u>Single event effects (SEE)</u>. SEE shall be performed at initial qualification and after process or design changes which may affect radiation hardness (see table III and table IV). Upon qualification, manufacturers shall provide the verification test conditions from section 5 of method 1080 of MIL-STD-750 that were used to qualify the device for inclusion into section 6 of the slash sheet. End-point measurements shall be in accordance with table II. SEE characterization data shall be made available upon request of the qualifying or acquiring activity.

4.3 <u>Screening of encapsulated devices</u>. Screening of packaged devices shall be in accordance with table E-IV of MIL-PRF-19500, and as specified herein. The following measurements shall be made in accordance with table I herein. Devices that exceed the limits of table I herein shall not be acceptable.

Screen	Measu	ırement		
(1) (2)	JANS	JANTXV		
(3)	Gate stress test (see 4.3.1)	Gate stress test (see 4.3.1)		
(3)	Method 3470 of MIL-STD-750, E _{AS} (see 4.3.2)	Method 3470 of MIL-STD-750, E _{AS} (see 4.3.2)		
(3) 3c	Method 3161 of MIL-STD-750, thermal impedance, (see 4.3.3)	Method 3161 of MIL-STD-750, thermal impedance, (see 4.3.3)		
9	Subgroup 2 of table I herein	Not applicable		
10	Method 1042 of MIL-STD-750, test condition B	Method 1042 of MIL-STD-750, test condition B		
11	Subgroup 2 of table I herein. $\Delta I_{GSSF1} = \pm 20$ nA dc or ± 100 percent of initial value, whichever is greater. $\Delta I_{GSSR1} = \pm 20$ nA dc or ± 100 percent of initial value, whichever is greater. $\Delta I_{DSS1} = \pm 10$ μ A dc or ± 100 percent of initial value, whichever is greater.	Subgroup 2 of table I herein.		
12	Method 1042 of MIL-STD-750, test condition A	Method 1042 of MIL-STD-750, test condition A		
13	Subgroups 2 and 3 of table I herein $\Delta I_{GSSF1} = \pm 20$ nA dc or ± 100 percent of initial value, whichever is greater. $\Delta I_{GSSR1} = \pm 20$ nA dc or ± 100 percent of initial value, whichever is greater. $\Delta I_{DSS1} = \pm 500$ nA dc or ± 100 percent of initial value, whichever is greater. $\Delta I_{DS(ON)1} = \pm 20$ percent of initial value. $\Delta V_{GS(TH)1} = \pm 20$ percent of initial value.	Subgroup 2 of table I herein $\Delta I_{\text{GSSF1}} = \pm 20 \text{ nA dc or } \pm 100 \text{ percent of initial value, whichever is greater.}$ $\Delta I_{\text{GSSR1}} = \pm 20 \text{ nA dc or } \pm 100 \text{ percent of initial value, whichever is greater.}$ $\Delta I_{\text{DSS1}} = \pm 500 \text{ nA dc or } \pm 100 \text{ percent of initial value, whichever is greater.}$ $\Delta I_{\text{DS}(\text{ON})1} = \pm 20 \text{ percent of initial value.}$ $\Delta I_{\text{CS}(\text{TH})1} = \pm 20 \text{ percent of initial value.}$		
17	For TO-257AA (T3 and D5 suffixes) and TO-276AA (U3 suffix) packages: Method 1081 of MIL-STD-750 (see 4.3.4), Endpoints: Subgroup 2 of table I herein.	For TO-257AA (T3 and D5 suffixes) and TO-276AA (U3 suffix) packages: Method 1081 of MIL-STD-750 (see 4.3.4), Endpoints: Subgroup 2 of table I herein.		

- (1) At the end of the test program, I_{GSSF1} , I_{GSSR1} , and I_{DSS1} are measured.
- (2) An out-of-family program to characterize IGSSF1, IGSSR1, IDSS1 and VGS(th)1 shall be invoked
- (3) Shall be performed anytime after temperature cycling, screen 3a; JANTXV does not need to be repeated in screening requirements.

4.3.	3.1 Gate stress test. Apply V_{GS} = 24 V minimum for t = 250 μ s minimum.									
4.3.	2 Single pulse avalanche energy (E _{AS}).									
a.	Peak current	I _{AS} = I _{D2} .								
b.	Inductance:	$ \left[\frac{2E_{AS}}{(I_{D2})^2} \right] \left[\frac{V_{BR} - V_{DD}}{V_{BR}} \right] $ mH minimum.								
C.	Gate to source resistor (R _{GS})	25 ≤ R _{GS} ≤ 200 Ω.								
d.	Supply voltage (V _{DD})	V_{DD} = 25 V dc, up to rated V_{DS} .								
* e.	Peak gate voltage (V _{GS})	20 V, up to maximum rated V _{GS} .								
f.	Initial case temperature	T _C = +25°C +10°C, -5°C.								
g.	Number of pulses to be applied	1 pulse minimum.								
3161		ance measurements shall be performed in accordance with method method for determining I_M , I_H , t_{HD} , t_{SW} , (and V_H where nerein.								
4.3.	4 <u>Dielectric withstanding voltage</u> .									
а	. Magnitude of test voltage	600V dc.								
b	. Duration of application of test voltage	15 seconds (min).								
С	. Points of application of test voltage	All leads to case (bunch connection).								
d	. Method of connection	Mechanical								
е	. Kilovolt-ampere rating of high voltage so	ource1,200 V.1,0 mA (min).								
f.	Maximum leakage current	1.0 mA.								
g	. Voltage ramp up time	500 V/second								
4.4	Conformance inspection. Conformance ins	spection shall be in accordance with MIL-PRF-19500.								

4.4.1 <u>Group A inspection</u>. Group A inspection shall be conducted in accordance with table E-V of MIL-PRF-19500 and table I herein.

- 4.4.2 <u>Group B inspection</u>. Group B inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VIA (JANS) and table E-VIB (JANTXV) of MIL-PRF-19500, and as follows.
 - 4.4.2.1 Quality level JANS (table E-VIA of MIL-PRF-19500).

Subgroup	Method	Condition
В3	1051	Test condition G, 100 cycles.
В3	2077	Scanning electron microscope (SEM).
B4	1042	Intermittent operation life, condition D, t_{on} = 30 seconds minimum.
B5	1042	Accelerated steady-state gate bias, condition B, V_{GS} = rated; T_A = +175°C, t = 24 hours minimum; or T_A = +150°C, t = 48 hours minimum.
B5	1042	Accelerated steady-state reverse bias, condition A, V_{DS} = rated; T_A = +175°C, t = 120 hours minimum; or T_A = +150°C, t = 240 hours minimum.
B5	2037	Test condition D.

4.4.2.2 Quality level JANTXV (table E-VIB of MIL-PRF-19500).

Subgroup	Method	Condition
B2	1051	Test condition G, 25 cycles.
В3	1042	Intermittent operation life, condition D, ton = 30 seconds minimum.

4.4.3 <u>Group C inspection</u>. Group C inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VII of MIL-PRF-19500 and as follows.

<u>Subgroup</u>	<u>Method</u>	Condition
C2	2036	Terminal strength is not applicable to the TO-276AA (U3 and U3C) package
C5	3161	See 4.3.3, R _{0JC} = 1.67 °C/W.
C6	1042	Intermittent operation life, condition D, ton = 30 seconds minimum.

- 4.4.4 <u>Group D inspection</u>. Group D inspection shall be conducted in accordance with table E-VIII of MIL-PRF-19500 and table II herein.
- 4.4.5 <u>Group E inspection</u>. Group E inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-IX of MIL-PRF-19500 and as specified in table III herein.
 - 4.5 Methods of inspection. Methods of inspection shall be as specified in the appropriate tables and as follows.
 - 4.5.1 Pulse measurements. Conditions for pulse measurement shall be as specified in section 4 of MIL-STD-750.

TABLE I. Group A inspection.

	Inspection 1/	MIL-STD-750		Symbol	Limits		Unit
		Method	Method Condition		Min	Max	
	Subgroup 1						
	Visual and mechanical inspection	2071					
	Subgroup 2						
	Thermal impedance 2/	3161	See 4.3.3	ZθJC			°C/W
*	Breakdown voltage drain to source	3407		V _{(BR)DSS}			
*	2N7647U3, U3C, T3, D5		Bias condition C, V _{GS} = 0 V, I _D = 1 mA dc		60		V dc
*	2N7648U3, U3C, T3, D5		Bias condition C, $V_{GS} = 0 \text{ V}$, $I_D = 1 \text{ mA}$ dc		100		V dc
	Gate to source voltage (threshold)	3403	V _{DS} ≥ V _{GS} , I _D = 1 mA dc	V _{GS(TH)1}	2.0	4.0	V dc
	Gate current	3411	V_{GS} = +20 V dc, bias condition C, V_{DS} = 0 V	I _{GSSF1}		+100	nA dc
	Gate current	3411	V _{GS} = -20 V dc, bias condition C, V _{DS} = 0 V	I _{GSSR1}		-100	nA dc
	Drain current	3413	V_{GS} = 0 V dc, bias condition C, V_{DS} = 80 percent of rated V_{DS} ,	I _{DSS1}		1.0	μA dc
	Static drain to source on-state resistance	3421	V_{GS} = 12 V dc, condition A, pulsed (see 4.5.1), I_D = I_{D2}	r _{DS(ON)1}			
*	2N7647U3, 2N7647U3C 2N7647T3, 2N7647D5					0.018 0.019	Ω
	2N7648U3, 2N7648U3C					0.019	Ω
	2N7648T3, 2N7648D5					0.035	Ω
	Forward voltage	4011	$V_{GS} = 0 \text{ V dc}$, condition A, $I_D = I_{D1}$	V _{SD}		1.2	V dc

See footnotes at end of table.

TABLE I. Group A inspection - Continued.

TABLE 1. Gloup A Inspection - Continued.										
	Inspection 1/		MIL-STD-750	Symbol	Lir	mits	Unit			
		Method	Condition		Min	Max				
	Subgroup 3 High temperature operation		T _C = T _J = +125°C							
	Gate current	3411	V _{GS} = ±20 V dc, bias condition C, V _{DS} = 0 V	I _{GSS2}		±200	nA dc			
	Drain current	3413	V _{GS} = 0 V dc, bias condition C, V _{DS} = 80 percent of rated V _{DS}	I _{DSS2}		10	μA dc			
*	Static drain to source on-state resistance 2N7647U3, 2N7647U3C 2N7647T3, 2N7647D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5	3421	V_{GS} = 12 V dc, condition A, pulsed (see 4.5.1), I_D = I_{D2}	rds(on)3		0.036 0.038 0.061 0.063	Ω Ω Ω			
	Gate to source voltage (threshold)	3403	V _{DS} ≥ V _{GS} , I _D = 1 mA dc	V _{GS(TH)2}	1.0		V dc			
	Low temperature operation		$T_C = T_J = -55$ °C							
	Gate to source voltage (threshold)	3403	$V_{DS} \ge V_{GS(TH)3}$, $I_D = 1$ mA dc	V _{GS(TH)3}		5.0	V dc			
	Subgroup 4									
*	Forward transconductance 2N7647U3, U3C, T3, D5 2N7648U3, U3C, T3, D5	3475	$I_D = I_{D2}$, $V_{DD} = 15 \text{ V dc (see 4.5.1)}$	g FS	20 14		S S			
	Switching Time Tests	3472	I_D = I_{D1} , V_{GS} = 12 V dc, R_G =7.5 Ω , V_{DD} = 50 percent rated V_{DS}							
*	Turn-On Delay Time 2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5		VDD - 30 percent rated VDS	td(on)		20 25 25	ns ns ns			
*	Rise Time 2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5			tr		40 56 35	ns ns ns			
*	Turn-Off Delay Time 2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5			td(off)		45 38 45	ns ns ns			
*	Fall Time 2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5			tf		30 27 30	ns ns ns			

See footnotes at end of table.

TABLE I. Group A inspection - Continued.

	TABLE I. Gloup A mapeolism - Continued.						
	Inspection <u>1</u> /	MIL-STD-750		Symbol	Limits		Unit
		Method	Condition		Min	Max	
	Subgroup 5						
	Safe operating area test	3474	See figure 6, tp = 10 ms min. V_{DS} = 80 percent of max. rated V_{DS}				
	Electrical measurements		See table I, subgroup 2				
	Subgroup 6						
	Not applicable						
	Subgroup 7						
	Gate charge	3471	Condition B, $I_D = I_{D1}$, $V_{GS} = 12 \text{ V dc}$ $V_{DD} = 50$ percent of rated V_{DS}				
	On-state gate charge and turn-off gate charge			Q _G			
*	2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5					45 48 44	nC nC nC
*	Gate to source charge (turn-on and turn-off) 2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5			Q _{GS}		14 25 20	nC nC
*	Gate to drain charge (turn-on and turn-off) 2N7647U3, U3C, T3, D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5			Q _{GD}		11 9 12	nC nC nC
	Reverse recovery time	3473	Condition A, di/dt = -100 A/ μ s, V _{DD} \leq 50 V, I _D = I _{D1}	t _{rr}			
*	2N7647U3, U3C, T3, D5 2N7648, U3, U3C, T3, D5					130 210	ns ns

 ^{1/} For sampling plan, see MIL-PRF-19500.
 2/ For end-point measurements, this test is required for the following subgroups:
 Group B, subgroups 2 and 3 (JANTXV).
 Group B, subgroups 3 and 4 (JANS).

Group C, subgroup 2 and 6. Group E, subgroup 1.

TABLE II. Group D inspection.

	Inspection		Cumbal			radiation Pos		radiation	Unit
	<u>1</u> / <u>2</u> / <u>3</u> / Metho		Conditions		R and F		R and F		1
					Min	Max	Min	Max	
	Subgroup 1								
	Not applicable								
	Subgroup 2		T _C = + 25°C						
	Steady-state total dose irradiation (V _{GS} bias) <u>4</u> /	1019	$V_{GS} = 12 V;$ $V_{DS} = 0$						
	Steady-state total dose irradiation (V _{DS} bias) <u>4/</u>	1019	V_{GS} = 0; V_{DS} = 80 percent of rated V_{DS} (pre-irradiation)						
	End-point electricals:								
	Breakdown voltage,	3407	Bias condition C, V _{GS} = 0;	$V_{(BR)DSS}$					
*	drain to source 2N7647U3, 2N7647U3C		I _D = 1 mA		60		60		V dc
*	2N7647T3, 2N7647D5 2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5				100		100		V dc
	Gate to source voltage (threshold)	3403	$V_{DS} \ge V_{GS}, I_D = 1 \text{ mA}$	$V_{\text{GS(th)1}}$	2.0	4.0	2.0	4.0	V dc
	Gate current	3411	Bias condition C, V_{GS} = +20 V; V_{DS} = 0	I _{GSSF1}		100		100	nA dc
	Gate current	3411	Bias condition C, V_{GS} = -20 V; V_{DS} = 0	I _{GSSR1}		-100		-100	nA dc
	Drain current	3413	Bias condition C, $V_{GS} = 0$ $V_{DS} = 80$ percent of rated V_{DS} (pre-irradiation)	I _{DSS}		1.0		1.0	μA dc
	Static drain to source on- state voltage	3405	$V_{GS} = 12 \text{ V}; I_D = I_{D2}$ condition A, pulsed (see 4.5.1)	$V_{DS(on)}$					
*	2N7647U3, 2N7647U3C 2N7647T3, 2N7647D5 <u>5</u> /		1.5.1)			0.522 0.532		0.522 0.532	V dc V dc
	2N7648U3, 2N7648U3C 2N7648T3, 2N7648D5 <u>5</u> /					0.748 0.770		0.748 0.770	V dc V dc
	Forward voltage source drain diode	4011	Bias condition A, $V_{GS} = 0$; $I_D = I_{D1}$	V_{SD}		1.2		1.2	V dc

^{1/} For sampling plan, see MIL-PRF-19500. 2/ Group D qualification may be performed Group D qualification may be performed prior to lot formation. Wafers qualified to these group D QCI requirements may be used for any other specification sheets utilizing the same die design.

^{3/} At the manufacturer's option, group D samples need not be subjected to the screening tests, and may be assembled in its qualified package or in any qualified package that the manufacturer has data to correlate the performance to the designated package.

Separate samples shall be pulled for each bias.

Group D samples are built and tested in T0-3 packages. The equivalent pre-radiation and post radiation limit for V_{DS(on)} in the T0-3 package is 0.792Vdc for the 2N7648U3, U3C, T3, D5 devices. For the 2N7647U3, U3C it is 0.580Vdc and for the 2N7647T3, D5 it is 0.560Vdc.

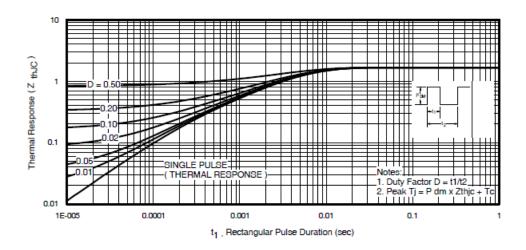
TABLE III. Group E inspection (all quality levels) for qualification or re-qualification only.

Inspection		Sample	
Inspection	Method	Conditions	plan
Subgroup 1			45 devices c = 0
Temperature cycling	1051	-55°C to +150°C, 500 cycles	
Hermetic seal Fine leak Gross leak	1071	As applicable.	
Electrical measurements		See table I, subgroup 2 herein.	
Subgroup 2 1/			45 devices c = 0
Steady-state gate bias	1042	Condition B, 1,000 hours.	C = 0
Electrical measurements		See table I, subgroup 2 herein.	
Steady-state reverse bias	1042	Condition A, 1,000 hours.	
Electrical measurements		See table I, subgroup 2 herein.	
Subgroup 3			n = 45, c = 0
Not applicable			
Subgroup 4			Sample size N/A
Thermal impedance curves		See MIL-PRF-19500.	IN/A
Subgroup 5			
Not applicable			
Subgroup 10			22 devices
Commutating diode for safe operating area test procedure for measuring dv/dt during reverse recovery of power MOSFET transistors or insulated gate bipolar transistors	3476		c = 0

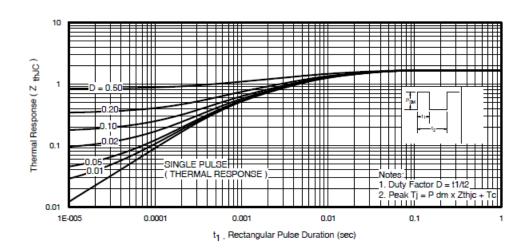
^{1/} A separate sample for each test shall be pulled.

^{2/} Group E qualification of SEE testing may be performed prior to lot formation. Qualification may be extended to other specification sheets utilizing the same structurally identical die design.

^{3/} Device qualification to a higher level linear energy transfer (LET) is sufficient to qualify all lower level LETs.

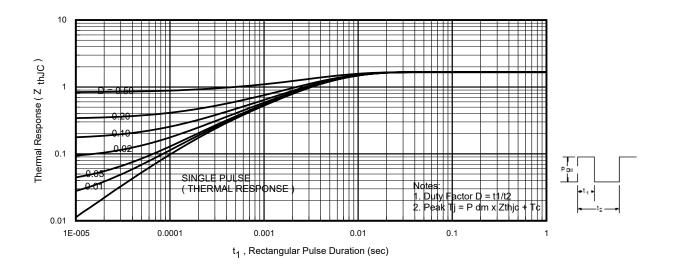


2N7647U3, 2N7647U3C.

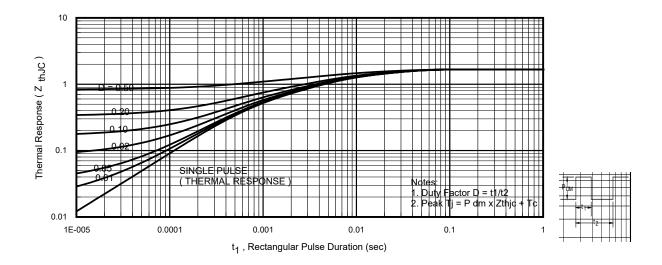


2N7647T3, 2N7647D5

FIGURE 4. Thermal response curve.



2N7648U3, 2N7648U3C.



2N7648T3, 2N7648D5

FIGURE 4. Thermal response curve - continued.

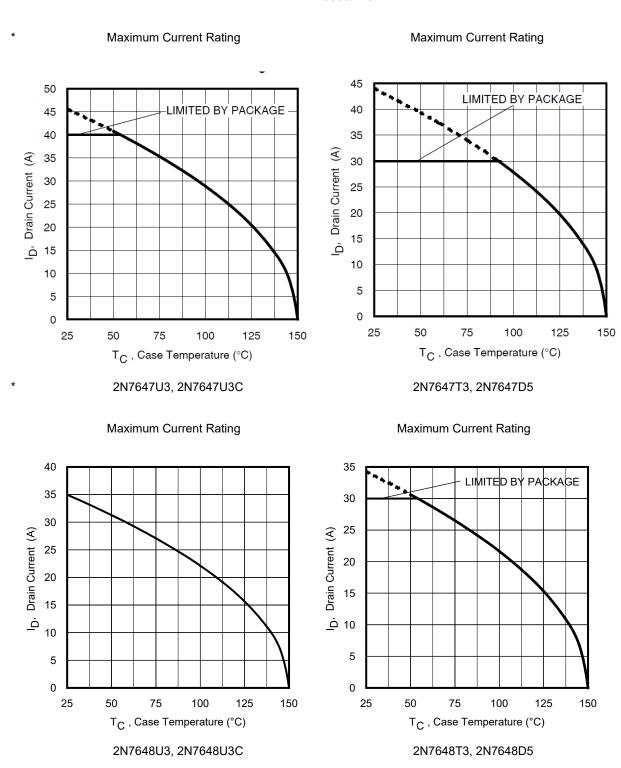


FIGURE 5. Maximum drain current versus case temperature graphs.

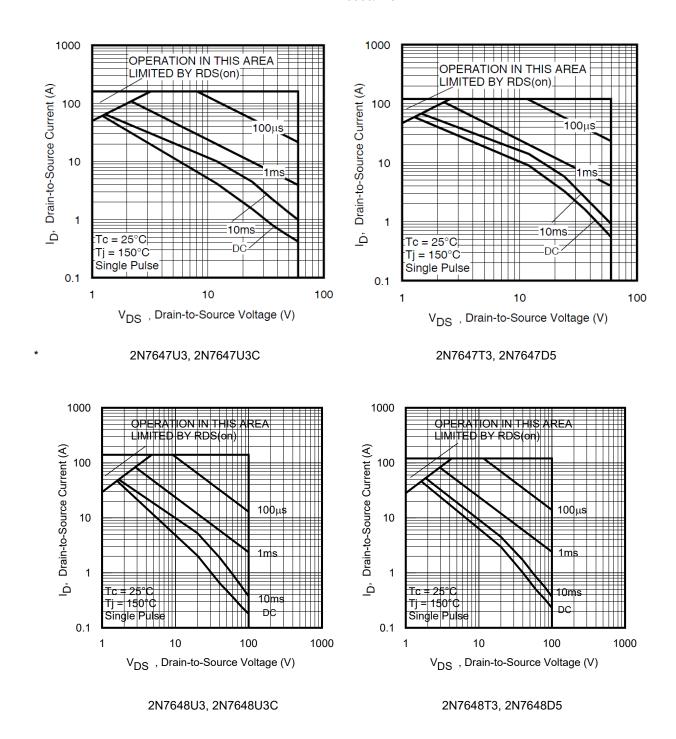


FIGURE 6. Safe operating area graph.

5. PACKAGING

5.1 <u>Packaging</u>. For acquisition purposes, the packaging requirements shall be as specified in the contract or order (see 6.2). When packaging of materiel is to be performed by DoD or in-house contractor personnel, these personnel need to contact the responsible packaging activity to ascertain packaging requirements. Packaging requirements are maintained by the Inventory Control Point's packaging activities within the Military Service or Defense Agency, or within the Military Service's system commands. Packaging data retrieval is available from the managing Military Department's or Defense Agency's automated packaging files, CD-ROM products, or by contacting the responsible packaging activity.

6. NOTES

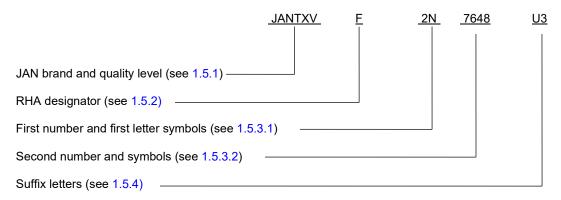
(This section contains information of a general or explanatory nature that may be helpful, but is not mandatory. The notes specified in MIL-PRF-19500 are applicable to this specification.)

- 6.1 <u>Intended use</u>. Semiconductors conforming to this specification are intended for original equipment design applications and logistic support of existing equipment.
 - 6.2 Acquisition requirements. Acquisition documents should specify the following:
 - a. Title, number, and date of this specification.
 - b. Packaging requirements (see 5.1).
 - c. Lead finish (see 3.4.1).
 - d. The complete PIN, see 1.5 and 6.6.
 - e. For acquisition of RHA designated devices, table II, subgroup 1 testing of group D herein is optional. If subgroup 1 is desired, it should be specified in the contract or order.
 - f. If SEE testing data is desired, it should be specified in the contract or order.
 - g. If specific SEE characterization conditions are desired (see section 6.7 and table IV), manufacturer's cage code should be specified in the contract or order.
- 6.3 <u>Qualification</u>. With respect to products requiring qualification, awards will be made only for products which are, at the time of award of contract, qualified for inclusion in Qualified Manufacturers List (QML 19500) whether or not such products have actually been so listed by that date. The attention of the contractors is called to these requirements, and manufacturers are urged to arrange to have the products that they propose to offer to the Federal Government tested for qualification in order that they may be eligible to be awarded contracts or orders for the products covered by this specification. Information pertaining to qualification of products may be obtained from DLA Land and Maritime, ATTN: VQE, P.O. Box 3990, Columbus, OH 43218-3990 or e-mail vqe.chief@dla.mil. An online listing of products qualified to this specification may be found in the Qualified Products Database (QPD) at https://qpldocs.dla.mil.

* 6.4 <u>Substitution information</u>. Devices covered by this specification are substitutable for the manufacturer's and user's Part or Identifying Number (PIN) (without JAN and RHA prefix). This information in no way implies that manufacturer's PINs are substitutable for the military PIN.

Preferred types military PIN	Commercial PIN
2N7647U3	IRHNJ9A7034
2N7647U3C	IRHNJC9A7034
2N7647T3	IRHYS9A7034CM
2N7647D5	IRHYB9A7034CM
2N7648U3 2N7648U3C 2N7648T3 2N7648D5	IRHNJ9A7130 IRHNJC9A7130 IRHYS9A7130CM IRHYB9A7130CM

6.5 PIN construction example. The PINs for encapsulated devices are constructed using the following form.



* 6.6 List of PINs. The following is a list of possible PINs (without JAN brand) available on this specification sheet.

JANTXVF2N7647U3	JANTXVF2N7647U3C	JANTXVF2N7647T3	JANTXVF2N7647D5
JANTXVR2N7647U3	JANTXVR2N7647U3C	JANTXVR2N7647T3	JANTXVR2N7647D5
JANSF2N7647U3	JANSF2N7647U3C	JANSF2N7647T3	JANSF2N7647D5
JANSR2N7647U3	JANSR2N7647U3C	JANSR2N7647T3	JANSR2N7647D5
JANTXVF2N7648U3	JANTXVF2N7648U3C	JANTXVF2N7648T3	JANTXVF2N7648D5
JANTXVR2N7648U3	JANTXVR2N7648U3C	JANTXVR2N7648T3	JANTXVR2N7648D5
JANSF2N7648U3	JANSF2N7648U3C	JANSF2N7648T3	JANSF2N7648D5
JANSR2N7648U3	JANSR2N7648U3C	JANSR2N7648T3	JANSR2N7648D5

The PIN is also available without a RHA designator.

6.7 Application data.

6.7.1 Manufacturer specific irradiation data. Each manufacturer qualified to this specification sheet has characterized its devices to the requirements of MIL-STD-750 method 1080 and as specified herein. Since each manufacturer's characterization conditions can be different and can vary by the version of method 1080 qualified to, the MIL-STD-750 method 1080 revision version date and conditions used by each manufacturer for characterization have been listed here (see table IV) for information only. SEE conditions and figures listed in section 6 are current of the date of this specification sheet, please contact the manufacturer for the most recent conditions.

TABLE IV. Manufacturers characterization conditions.

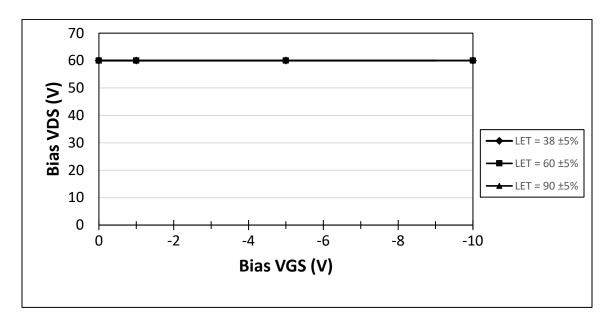
Manufacturers	Inspection	MIL-STD-750				
CAGE		Method	Conditions	Sample plan		
69210	SEE <u>1</u> /	1080	See MIL-STD-750 method 1080 and figure 7	3 devices		
(Data is based on a test report	Pre SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			
date of July 2018, date code of 1620)	SEE irradiation		Fluence = 3E5 ±20 percent ions/cm ² Flux = 4E3 to 4E4 ions/cm ² /sec, temperature = 25 ±5°C			
,	2N7648U3, 2N7648U3C, 2N7648T3,		Surface LET = 36.95 MeV-cm2/mg $\pm 5\%$, range = 50.75 μ m $\pm 7.5\%$, energy = 418 MeV $\pm 7.5\%$			
	2N7648D5		In-situ bias conditions: V _{DS} = 100 V and V _{GS} = -20V			
			(Typical 4.98 MeV/Nucleon at Texas A & M Cyclotron)			
	Post SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			
	SEE <u>1</u> /	1080	See MIL-STD-750 method 1080	3 devices		
	Pre SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			
	SEE irradiation		Fluence = 3E5 ±20 percent ions/cm ² Flux = 4E3 to 4E4 ions/cm ² /sec, temperature = 25 ±5°C			
	2N7648U3, 2N7648U3C, 2N7648T3, 2M7648D5		Surface LET = 59.8 MeV-cm2/mg $\pm 5\%$, range = 60.8 μ m $\pm 7.5\%$, energy = 755 MeV $\pm 7.5\%$ In-situ bias conditions: V_{DS} = 100 V and V_{GS} = 14 V;			
	21111 0 1020		Typical 5.85 MeV/Nucleon at Texas A & M Cyclotron)			
	Post SEE Electrical measurements		I _{GSSF1} , I _{GSSR1} , and I _{DSS1} in accordance with table I, subgroup 2			
69210	SEE <u>1</u> /	1080	See MIL-STD-750 method 1080 and figure 7	3 devices		
	Pre SEE Electrical measurements		I _{GSSF1} , I _{GSSR1} , and I _{DSS1} in accordance with table I, subgroup 2			
	SEE irradiation		Fluence = 3E5 ±20 percent ions/cm ² Flux = 4E3 to 4E4 ions/cm ² /sec, temperature = 25 ±5°C			
	2N7648U3, 2N7648U3C, 2N7648T3,		Surface LET = 89.75 MeV-cm2/mg ±5%, range = 82.25 μm ±7.5%, energy = 1518.5 MeV ±7.5%			
	2N7648D5		In-situ bias conditions: V_{DS} = 100 V and V_{GS} = -5 V			
			(Typical 7.7 MeV/Nucleon at Texas A & M Cyclotron)			
	Post SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			

See footnote at end of table.

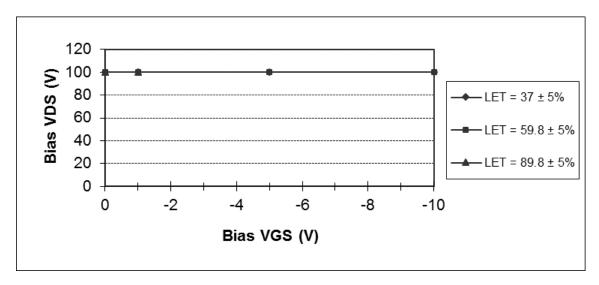
 ${\sf TABLE\ IV.}\ \ \underline{\sf Manufacturers\ characterization\ conditions}\ \hbox{-}\ continued.$

Manufacturers	Inspection	MIL-STD-750				
CAGE		Method	Conditions	plan		
69210	SEE <u>1</u> /	1080	See MIL-STD-750 method 1080 and figure 7	3 devices		
(Data is based on a test report	Pre SEE Electrical measurements		I _{GSSF1} , I _{GSSR1} , and I _{DSS1} in accordance with table I, subgroup 2			
date of January 2019, date code of 1733)	SEE irradiation		Fluence = 3E5 ±20 percent ions/cm ² Flux = 4E3 to 4E4 ions/cm ² /sec, temperature = 25 ±5°C			
code of 1733)	2N7647U3, 2N7647U3C, 2N7647T3, 2N7647D5		Surface LET = 38 MeV-cm2/mg ±5%, range = 43 µm ±7.5%, energy = 355 MeV ±7.5%			
	211104110, 211104120		In-situ bias conditions: V_{DS} = 60 V and V_{GS} = -10 V			
			(Typical 4.23 MeV/Nucleon at Texas A & M Cyclotron)			
	Post SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			
	SEE <u>1</u> /	1080	See MIL-STD-750 method 1080	3 devices		
	Pre SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			
	SEE irradiation		Fluence = 3E5 ±20 percent ions/cm ² Flux = 4E3 to 4E4 ions/cm ² /sec, temperature = 25 ±5°C			
	2N7647U3, 2N7647U3C, 2N7647T3, 2N7647D5		Surface LET = 60 MeV-cm2/mg ±5%, range = 60 µm ±10%, energy = 753MeV ±7.5%			
	2111 0 11 10, 2111 0 11 20		In-situ bias conditions: $V_{DS} = 60 \text{ V}$ and $V_{GS} = -10 \text{ V}$;			
			(Typical 5.84 MeV/Nucleon at Texas A & M Cyclotron)			
	Post SEE Electrical measurements		IGSSF1, IGSSR1, and IDSS1 in accordance with table I, subgroup 2			
	SEE <u>1</u> /	1080	See MIL-STD-750 method 1080 and figure 7	3 devices		
	Pre SEE Electrical measurements		I _{GSSF1} , I _{GSSR1} , and I _{DSS1} in accordance with table I, subgroup 2			
	SEE irradiation		Fluence = 3E5 ±20 percent ions/cm ² Flux = 4E3 to 4E4 ions/cm ² /sec, temperature = 25 ±5°C			
	2N7647U3, 2N7647U3C, 2N7647T3, 2N7647D5		Surface LET = 90 MeV-cm2/mg ±5%, range = 82 µm ±7.5%, energy = 1515 MeV ±10%			
	214704713, 214704713		In-situ bias conditions: $V_{DS} = 60 \text{ V}$ and $V_{GS} = -1 \text{ V}$			
			(Typical 7.69 MeV/Nucleon at Texas A & M Cyclotron)			
	Post SEE Electrical measurements		I _{GSSF1} , I _{GSSR1} , and I _{DSS1} in accordance with table I, subgroup 2			
Upon qualif	ication, all manufacture	ers will pr	ovide the verification test conditions to be added to this table).		

^{1/} IGSSF1, IGSSR1, and IDSS1 parameters were examined before and following SEE irradiation to determine acceptability for each bias conditions. Other test conditions in accordance with table I, subgroup 2, may be performed at the manufacturer's option.



2N7647U3, 2N7647U3C, 2N7647T3, 2N7647D5



2N7648U3, 2N7648U3C, 2N7648T3, 2N7648D5

FIGURE 7. SEE safe operating area graph.

- 6.8 Request for new types and configurations. Requests for new device types or configurations for inclusions in this specification sheet should be submitted to: DLA Land and Maritime, ATTN: VAC, Post Office Box 3990, Columbus, OH 43218-3990 or by electronic mail at Semiconductor@dla.mil or by facsimile (614) 692-6939 or DSN 850-6939.
- * 6.9 <u>Changes from previous issue</u>. The margins of this specification are marked with asterisks to indicate where changes from the previous issue were made. This was done as a convenience only and the Government assumes no liability whatsoever for any inaccuracies in these notations. Bidders and contractors are cautioned to evaluate the requirements of this document based on the entire content irrespective of the marginal notations and relationship to the last previous issue.

Custodians:

Army - CR Navy - EC Air Force - 85 NASA - NA DLA - CC Preparing activity: DLA - CC

(Project 5961-2019-100)

Review activity: Army - AV, MI Air force - 19

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